



Session Title:	[TF3] Frontier Metrology and Modeling V
Session Date:	November 21 (Tue.), 2023
Session Time:	14:05-16:05
Session Room:	Room F (Sicily Room, 1F)
Session Chair:	Prof. Hyungtak Seo (Ajou Univ., Korea)

[TF3-1] [Invited]

14:05-14:35

Atomistic Simulation of Semiconductor Processing Using Machine Learning Potentials

Seungwu Han (Seoul Nat'l Univ., Korea)

[TF3-2] [Invited]

14:35-15:05

The Optical System and Analysis for Thickness and Transition Zone Measurement of Epitaxial Layer

Yoonjong Park and Minyoung Lee (Semilab Korea Co., Ltd., Korea)

[TF3-3] [Invited]

15:05-15:35

Inline Convergence AFM Solutions for Advanced Packaging

Sang-Joon Cho, Seongoh Kim, Ahjin Cho, and ByungWoon Ahn (Park Systems, Korea)

[TF3-5] [Invited]

15:35-16:05

Improved Semiconductor Nanodevice Metrology with Next Generation Atom Probe

A. D. Giddings (AMETEK Korea Co. Ltd., Korea)